

Topics in CGI V

**Computer Graphics, Image processing and computer Vision
Division of Computer Information Engineering**

**Lee Byung Gook, Dongseo Univ., Busan, Korea
lbg@dongseo.ac.kr**

2009.8.20~21

**The JSPS/KOSEF Core University Program Seminar
on Next Generation Internet
TEMF Hotel, Gyongju, Korea**

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KOREA



Top Ten & To the World
너의 가슴에 세계를 담아라!

1992~2001

- 1995. 3 동서학원 설립
- 1992. 3 개교설립자 장성만 박사 및 재회 입학식(8개 학과 400명)
- 1996. 2 재회 학우수서식
- 1996. 3 동서대학교에서 동서대학교로 교명 변경
- 1996. 6 C.T. VISION 2000 선포
- 1996. 7 동아일보 주관 대학 정보화 경쟁 우수대학으로 선정
- 국립서울산업대(Tech. Corps) 청원
- 1996. 10 독일비엔나공과대 공명학과장(석·박사 학위) / 교육부평가 '세계화·정보화 부문 우수대학'으로 선정
- 1997. 2 교육의 세계화 선언 및 상징문 건립
- 1997. 5 뉴욕강 화랑봉사단 창단
- 1997. 11 한·독 공동연구센터 개소
- 1998. 5 독일 무인발에 현지 공동연구센터 개소 / 연공인 자비센터 개소
- 1998. 9 교육부평가 교육개혁 '대학과 지역사회의 연계 분야' 우수대학으로 선정
- 1999. 2 제시대 유망권 총장 취임
- 1999. 9 민선초보선대 개관
- 1999.10 디지털디자인대학원 석·박사과정 인가
- 1999.11 Dream Engineering Valley 개관
- 2000. 3 종합정보시스템(DAKOTAS)대중서 / 학생문화관 준공 / 대학원평가 '교육정책 시효성시행, 대학원평가' 우수대학 선정
- 2000. 7 산업자원부 주관 '영남권 디지털산업 거점대학' 선정(DIC)
- 2000. 8 산업자원부 주관 '신산업 고공인력 및 기술전문인력 양성 기관' 선정 / 교육부평가 '이공계 연구소 기지제 청년학 지원사업' 선정
- 2000. 9 교육부평가 '대학별 자체 교육개혁 실천 분야' 우수대학 선정
- 2001. 6 교육부평가 '이공계 연구소 기지제 청년학 지원 사업' 선정
- 2001. 7 소프트웨어 전문대학원 설립인가
- 2001. 8 교육인적자원부 평가 '대학별 자체교육개혁 실천분야' 우수대학 선정
- 2001.11 Mobile Campus 구축

- Mar. 1965 Dongseo Academic Institute Founded
- Mar. 1992 Dongseo College of Technology was established (8 majors with 400 students).
- Feb. 1996 The first commencement ceremony.
- Mar. 1996 Dongseo University of Technology was renamed Dongseo University.
- Jun. 1996 C.T. VISION 2000 was declared.
- Jul. 1996 Chosen as the Best Information University by Donga Daily Newspaper / International Technology Corps was organized.
- Oct. 1996 Dual degree program with Technical University of Berlin (MA and Ph.D.) began. / Chosen as the Best Information and Globalized University by the Ministry of Education
- Feb. 1997 Declared "Globalization" of Education and built a memorial sculpture.
- May 1997 Nak-dong River Environment Protection Corps was organized.
- Nov. 1997 Korea-Germany Joint Research Center opened.
- May 1998 The Joint Research Center at Lukenwalde, Germany opened. / Java Center authorized by Sun opened.
- Feb. 1998 Chosen as the Best Educational University by the Ministry of Education.
- Feb. 1999 President Park Dong Soon was inaugurated.
- Sep. 1999 Minsok Sports Center opened.
- Oct. 1999 Approval of MA and Ph.D. programs at the graduate school of Digital Design
- Nov. 1999 Dream E. Valley opened.
- Mar. 2000 The unified information system, DAKOTAS, opened. / Student Union completed / Chosen as the Best University in the fields of education, social services, and graduate school by the Ministry of Education.
- Jul. 2000 Chosen as the base university for digital design in Youngnam Province.
- Aug. 2000 Chosen as the Institute for fostering high-class manpower and technical experts in the footwear field by the Ministry of Commerce, Industry and Energy. / Support received for advancement of apparatus and materials in the science and engineering field by the Ministry of Education and Human Resources.
- Sep. 2000 Chosen as the best university in the field of "self-practice of the university reform plans" by the Ministry of Education and Human Resources.
- Jun. 2001 Support received for advancement of apparatus and materials in the science and engineering field by the Ministry of Education and Human Resources.
- Jul. 2001 Approval of opening of the Graduate School of Software.
- Aug. 2001 Chosen as the best university in the field of "self-practice of the university reform plans" by the Ministry of Education and Human Resources.
- Nov. 2001 Establishment of the Mobile Campus.

2002~2005

- 2002. 2 한국대학교육협의회 주관 '교양교육'과 '다문화교육' 평가에서 전국 최우수 대학에 선정
- 2002. 9 한국산업인력공단 일원취업업체 10 연구기관 선정
- 2002. 11 교육인적자원부 지방대학 육성지원대학 선정
- 2003. 2 제시대 유망권 총장 취임
- 2003. 3 정보통신부 IT 학과 교과과정평가우수사업 선정
- 2003. 3 뉴질랜드관광 원공, 개교 10주년 기념식
- 2003. 7 교육인적자원부 지방대학 육성지원대학 선정
- 2003. 8 산업자원부 지역혁신센터(TIC) 선정
- 2003. 9 Japan Center 개소
- 2004. 6 교육인적자원부 지방대학혁신성장화사업(NUR) 5대 사업단 선정
- 2004. 7 교육인적자원부 학교기업지원대상대학 선정
- 2004. 8 산업자원부 지역혁신성장화사업대학 선정
- 2005. 2 대학종합평가 '발전성과 및 비전' 분야 전국 1위
- 2005. 2 u-Campus 구축 및 Ubiquitous 체험관 개관식
- 2005. 5 한국문화관광연구원 문화관광 특성화 교육기관 선정
- 2005. 6 정보통신연구진흥원 (KITA) 재임용 조형지원사업우수대학 선정
- 2005. 6 독일 에버링겐대학과 공동학위과정 협정
- 2005. 6 삼성경제연구소 주관 '대학혁신과 경쟁력' 대학우수 사례 발표(제4회) 동서대학교 특성화프로그램
- 2005. 7 동서대 북경(중국) 고베(일본)대학 공동연구 실에 대한 협정서 조인
- 2005. 8 핀란드 오울루대학 공동학위프로그램 개설
- 2005. 10 중국 선전시 공명학위프로그램 협정 체결
- 2005. 10 중국 중산대 학술교류 협정 체결

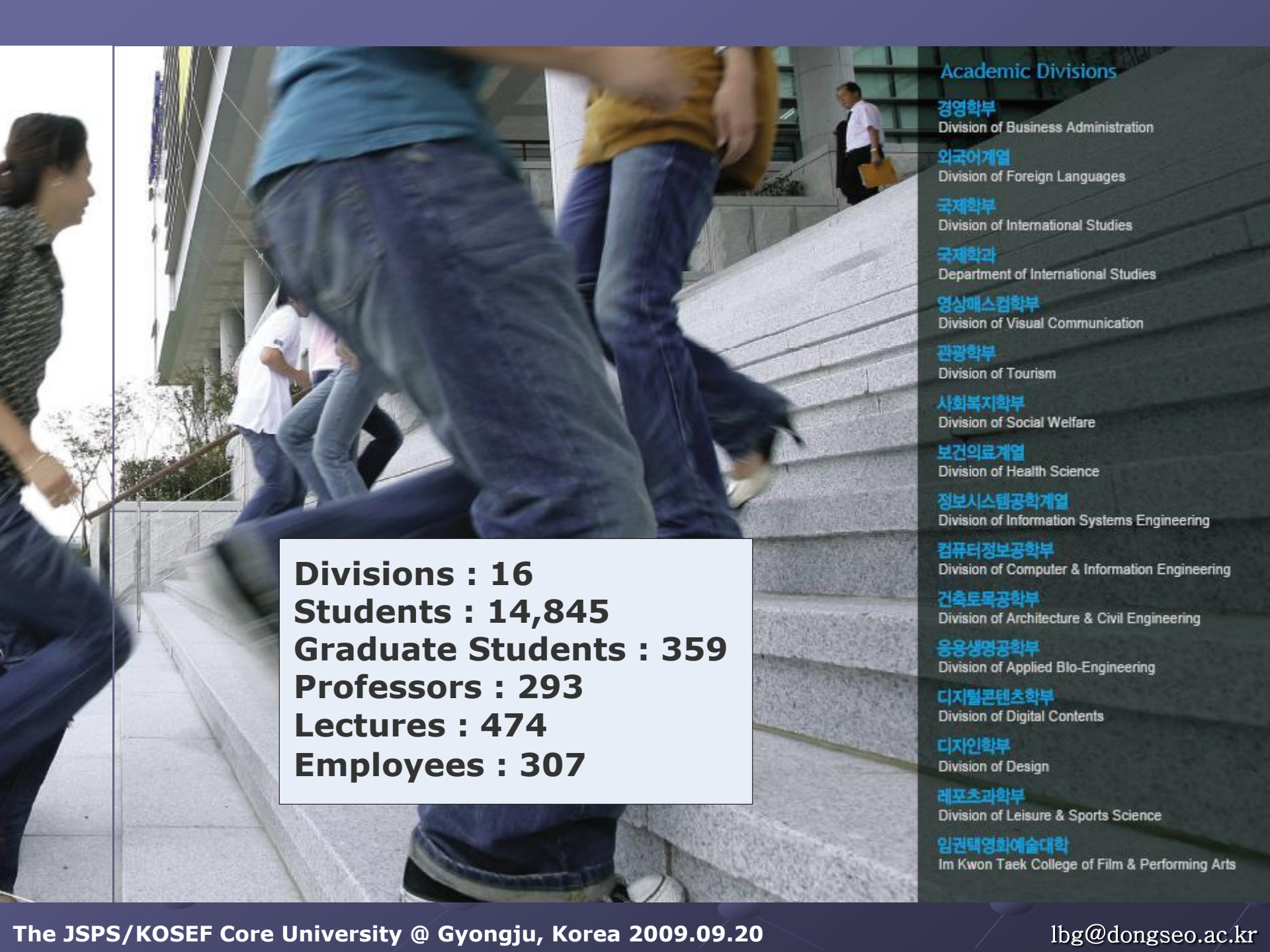
- Feb. 2002 Selected as one of the best universities in the fields of Liberal Arts and Design Education by the Korea Council for University Education.
- Sep. 2002 Chosen as the IT Training Institute for employment in Japan by the Korea Industrial Human Resources Cooperation.
- Nov. 2002 Financial support received for the development of regional universities by the Ministry of Education and Human Resources.
- Feb. 2003 President Park Dong Soon was inaugurated.
- Mar. 2003 Support received for curriculum development for IT majors by the Ministry of Information and Communication.
- Mar. 2003 New Millennium Building opened.
- Jul. 2003 Financial support received for the development of regional universities by the Ministry of Education and Human Resources.
- Aug. 2003 Selected as a Technology Innovation Center(TIC) by the Ministry of the Commerce, Industry and Energy.
- Sep. 2003 Japan Center opened.
- Jun. 2004 Won five business proposals for the New University for Regional Innovation (NURI) offered by the Ministry of Education and Human Resources.
- Jul. 2004 Support received for University Business Development from the Ministry of Education and Human Resources.
- Aug. 2004 Selected as the University for Regional Innovation System by the Ministry of Commerce, Industry and Energy.
- Feb. 2005 Ranked first in "Development Strategy and Vision" in the Comprehensive University Evaluation.
- May. 2005 Built U-Campus and had an opening ceremony of The Ubiquitous Experience Hall.
- May. 2005 Selected as an educational institute specialized in cultural content production by Korea Culture & Content Agency.
- Jun. 2005 Selected for Overseas Professor Invitation Project in IT (Best Practice) by Institute of Information Technology / Assessment.
- Jun. 2005 Signed a dual degree program with Erlangen University of Germany.
- Jun. 2005 Presented a case study on "University Innovation and Competitiveness" organized by Samsung Economic Research Institute.
- Jul. 2005 Signed joint research & development projects with Beijing Institute of Technology, Kobe College of Liberal Arts.
- Aug. 2005 Opened dual degree program with University of Oulu in Finland.
- Oct. 2005 Signed a dual degree program with Shenzhen University in China.
- Oct. 2005 Academic exchange agreement with Sun Yat-Sen University in China.

2006~2007

- 2006. 1 미국 조지아성탄대학교 학술교류협정 체결
- 2006. 2 해외인사지원 취업지원사업에 선정(2004년 2005년 이미 3년 연속)
- 2006. 2 호주 신시몬스트라대학교 학술교류협정 체결
- 2006. 4 교육인적자원부 2단계 BK21 사업에 3개 팀 선정
- 2006. 5 스페인 톨레도 공과대학교 학술교류협정 체결
- 2006. 6 인도네시아 테크노리크리안대학교와 Tech. Corps 관련 협정 체결
- 2006. 6 2006 세계 대학 총장 회의 개최
- 2006. 6 개교 15주년 기념식
- 2006. 6 중국 중산대학교 학술교류협정 체결
- 2006. 6 일본 리츠메이칸대학교 학술교류협정 체결
- 2006. 6 미국 호프국제대학교 학술교류협정 체결
- 2006. 6 동서대 일본연구센터와 동경연구회 학술교류협정 체결
- 2006. 7 중국 노동현(학과의) 학술교류협정 체결
- 2006. 7 독일 비엔나(예술대학과) 디자인대학, 교향악단원 협정 체결
- 2006. 9 한·일 6개 대학 공동연구센터 개최
- 2006. 10 미국 호프국제대학교 교향악단원 협정 체결
- 2006. 10 중국 중남대(정장평대학) 학술교류 협정 체결
- 2006. 11 부산시와 독일 '네 그로브스탈트' 과 공동으로 유비엔티스 및 VRGO 기술개발 연구의 산출물 우리 대학에 설립
- 2006. 12 부산 경남 최초의 IP6 기반의 와이브로 기지국 개통
- 2007. 2 제시대 비평소 총장 취임
- 2007. 2 제2회 학우수서식
- 2007. 2 2007년도 입학식
- 2007. 4 동서대 경주 야간부 개원
- 2007. 6 중국 중남대(정장평대학) 학원 협치대학 설립
- 2007. 6 중국 웨이팡과학기술대학에 한중 국제유학원 개원
- 2007. 7 일본(에히메)예술대학 설립
- 2007. 8 국제화협력 개관
- 2007. 9 민선초보선 개관
- 2007. 10 일본(후쿠오카) 연구소 개소

- Jan. 2006 Academic Exchange Agreement with University of George Washington in the US
- Feb. 2006 Selected for Overseas Internship Support (consecutive 3years, 2004-6)
- Feb. 2006 Academic Exchange Agreement with University of Sunshine Coast in Australia
- Apr. 2006 3 Teams were selected for "Phase 2 BK21" by Ministry of Education & Human Resources Development
- May. 2006 Academic Exchange Agreement with Lulea University of Technology in Sweden
- Jun. 2006 Academic Exchange Agreement on Tech. Corps related Fields with Petra Christian University in Indonesia
- Jun. 2006 Held World University Presidents Forum 2006
- Jun. 2006 Celebration of the 15th Anniversary of the University Foundation
- Jun. 2006 Academic Exchange Agreement with Sun Yat-Sen University in China
- Jun. 2006 Academic Exchange Agreement with Ritsumeikan University in Japan
- Jun. 2006 Academic Exchange Agreement with Hope International University in the US
- Jun. 2006 Academic Exchange Agreement between Dongseo University Japan Center and Sejong Institute
- Jul. 2006 Academic Exchange Agreement with Nottingham University in China
- Jul. 2006 Agreement on Exchange Students of Division of Digital Design with Kunshhochschule Berlin-Weensee in Germany
- Sep. 2006 Held 6 Universities Joint Seminar of Korea-Japan
- Oct. 2006 Agreement on Exchange Students with Hope International University in the US
- Oct. 2006 Academic Exchange Agreement with Zhongnan University of Economics and Law in China
- Nov. 2006 Establishment of IAI(The Institute for Ambient Intelligence) jointly with Busan Metropolitan City and 'In' Graphics' in Germany
- Dec. 2006 Opened IP6 based WiBro Radio Access Station firstly in the area of Busan City and Kyungnam Province
- Feb. 2007 Inauguration of the 6th President, Dong-Soon Park
- Feb. 2007 The 12th Laureation
- Feb. 2007 Entrance Ceremony
- Apr. 2007 Opened Dongseo University Confucius Institute
- Jun. 2007 Establishment of Joint College with Zhongnan University of Economics and Law in China
- Opened 'Korea-China Overseas Education Center' at Weifang Science & Technology Vocational College in China
- Jul. 2007 Establishment of In Kwon Taek College of Film & Performing Arts
- Aug. 2007 Opened International House
- Sep. 2007 Opened Minsok Library
- Oct. 2007 Opened In Kwon Taek's Film Research Center





Divisions : 16
Students : 14,845
Graduate Students : 359
Professors : 293
Lectures : 474
Employees : 307

Academic Divisions

경영학부

Division of Business Administration

외국어계열

Division of Foreign Languages

국제학부

Division of International Studies

국제학과

Department of International Studies

영상매스컴학부

Division of Visual Communication

관광학부

Division of Tourism

사회복지학부

Division of Social Welfare

보건의료계열

Division of Health Science

정보시스템공학계열

Division of Information Systems Engineering

컴퓨터정보공학부

Division of Computer & Information Engineering

건축토목공학부

Division of Architecture & Civil Engineering

응용생명공학부

Division of Applied Bio-Engineering

디지털콘텐츠학부

Division of Digital Contents

디자인학부

Division of Design

레포츠과학부

Division of Leisure & Sports Science

임권택영화예술대학

Im Kwon Taek College of Film & Performing Arts



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The Second Stage of



Fostering A World-Class Talent

응용과학 컴퓨터학

첨단 영상콘텐츠 창작기술 개발사업팀

Advanced Technology for Visual Contents Production



Computer Graphics, Image Processing and Computer Vision Research Group (CGIV)

Members

- Professor : byung-gook lee, joon-jae lee, hwang-kyu yang, jaechil yoo, kwan-pyo ko, hoon yoo, kwang-min jeong, dong-hak shin
- Ph.D. Students : nam-woo kim
- M.S. Students : nam-seok choi, yong-hyeon hwang, seung-jae lee, du-cheol gang, neeraj sharma, seung-il han, yeong-mi jeon, jung-hye kwon, kyeong-ran kim, tan chun wei, chow hoo mun, teresa liew bao yng, liliana
- Internship Students : diong wei liam(Malaysia Multimedia Univ., 07.7~), mur liyana binti mohd marizd(Malaysia Multimedia Univ., 06.6~06.9), tee cheau mei(Malaysia Multimedia Univ., 06.6~06.9), thomas ebner(Tech. Univ. of Dresden, 05.10~06.6), andre bugay(Tech. Univ. of Dresden, 05.10~06.6), eileen(Malaysia Multimedia Univ., 05.6~05.10)
- B.S. Students : dong-hun choi, jung-woo lee, jong-hyun baek, sung-hyun kim, cho-hee jin
- Alumni : sang-jun cha(07.8), myoung-su yun(07.2), sang-ji kim(07.2), rae-won kang(07.2), lye wei shi(07.2), raghubansh bahadur gupta(07.2), kishore kunal(sona)(06.8), sang-jun lee(06.2), jee-hoon jung(06.2), woo-jong lim(05.2), hyo-min ahn(05.2), hong-ju cho(05.2), you-chun tang(05.2), woo-jin jung(05.2), in-ho baik(05.2), jae-sik kang(05.2), yun-li lee(04.8), seow-hui saw(04.8), hyun-woo park(04.8), seung-mok lee(04.8)

Research Fields - Schedule.

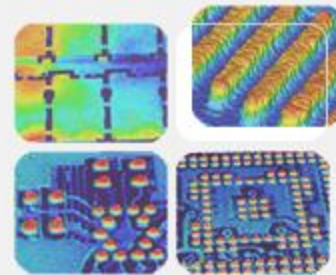
- Subdivision : kwan-pyo ko, yeong-mi jeon, jung-hye kwon, chow hoo mun
- E-spline : du-cheol gang, nam-woo kim, yeong-mi jeon
- Image Processing & Deinteracing : du-cheol gang, kyeong-ran kim, cho-hee jin
- Fingerprint Pattern Matching : nam-seok choi, neeraj sharma,
- Level Set : teresa liew bao yng, nam-woo kim
- Integral Image : dong-hak shin, yong-hyun hwang, tan chun wei
- Image Deformation : nam-seok choi, nam-woo kim
- Multi Touch Screen : nam-seok choi, yeong-mi jeon
- Laser Pointer Interaction : seung-jae lee, jung-woo lee
- PTZ Camera Control : seung-il han, jong-hyun baek
- Mobile Phone Keypad : seung-il han, du-cheol gang
- U-Frame Interaction : nam-woo kim, sung-hyun kim
- IS communication : dong-hun choi, jong-hyun baek
- USB Camera Hand Tracking : seung-il han, jung-hye kwon, jong-hyun baek
- Parametrization : nam-woo kim
- Polygonal Simplification : nam-woo kim
- FPD Mura Detection : yong-hyun hwang, tan chun wei
- Etc : yong-hyeon hwang

PARMI

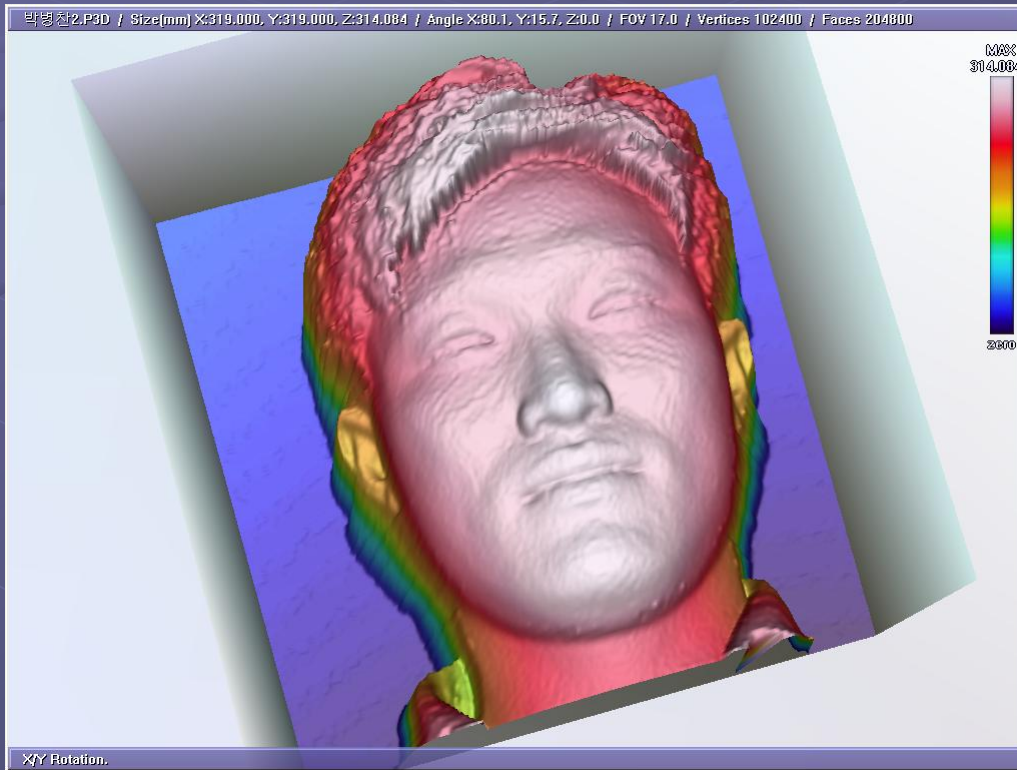
The Leader of 3D Solder Paste Inspection

Parmi is a world leader in 3 dimensional inspection for printed solder paste on PCB.

We provides a series of products to meet various customer needs. Top level quality and surprisingly high inspection speed of our machines are based on the unique 3D RSC (Range scan camera) sensor.

[HOME](#)





B-spline approximation

- Global approximation
- Quasi-interpolants

Multilevel B-spline approximation

Applications

- Surface approximation with scattered data
- Image representation and compression
- Filling holes in Range data

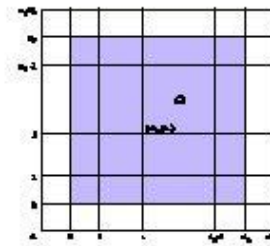
B-spline approximation

$$F(x, y) = \sum_{i=0}^{n_1-1} \sum_{j=0}^{n_2-1} c_{ij} B_i(x) B_j(y)$$

Given a set of scattered points $P = \{P_i\}$, $P_i = (x_i, y_i, z_i) \in P^3$ and $\Omega = [x_0, y_0, z_0] \times [x_1, y_1, z_1]$ be a rectangular domain in the xy -plane such that (x_i, y_i) is a point in Ω . Let Φ be a control lattice overlaid on a domain Ω . The control lattice Φ uses uniform tensor product grids over Ω . The knot intervals are uniform intervals defined as Δ_i in x -axis and Δ_j in y -axis. So, for uniform cubic B-splines case, degree of 3 and the set of knot vectors are defined as below:

$$\xi_x = \{-d, \xi_1, \dots, \xi_n, \xi_{n+1}, \dots, \xi_{n+1} + d\}$$

$$\xi_y = \{-d, \eta_1, \dots, \eta_m, \eta_{m+1}, \dots, \eta_{m+1} + d\}$$



Let Φ be a control lattice overlaid on a domain Ω .

Multilevel B-spline approximation

The algorithm runs in a multiresolution setting over uniform partitions such that the first surface f is composed of a sequence of surfaces of dyadic scales:

$$f = f_0 + f_1 + \dots + f_n$$

where $f_i \in S_i$, $i = 0, 1, \dots, n$, and S_0, S_1, \dots, S_n is a nested sequence of subspaces of S_0 .

The MSA algorithm serves as a smooth initial approximation f_0 to f defined on the coarsest control lattice $\Phi_0 = \Phi$ by applying the BA algorithm. To continue to the finer levels, table expansion on an input from [7]. The first approximation possibly lower level discrepancies of the data points in P .

In particular, f_1 leaves a deviation:

$$\Delta^1 f_0 = f - f_0(x, y) \text{ for } 0 \leq x \leq 1, 0 \leq y \leq 1$$

The next finer control lattice Φ_1 is then used to obtain function f_1 that approximates the difference $\Delta^1 f_0 = f - f_0(x, y, 0)$. First, the sum $f_0 + f_1$ yields a smaller deviation Δ^2 for each $(x, y) \in \Omega$:

$$\Delta^2 f_0 = f - f_0(x, y) - f_1(x, y) \text{ for } 0 \leq x \leq 1, 0 \leq y \leq 1$$

In general, for each level k in the hierarchy, the next set $\Delta^k f_{k-1} = f - f_{k-1}(x, y, 0)$ is approximated by a function f_k defined over the control lattice Φ_k , where

$$\Delta^k f_{k-1} = f - \sum_{i=0}^{k-1} f_i(x, y) = \Delta^{k-1} f_0 - f_{k-1}(x, y)$$

Quasi-interpolants

Given a function f , the basic problem of splines approximation is to determine B-spline coefficients $\{c_i\}$ such that:

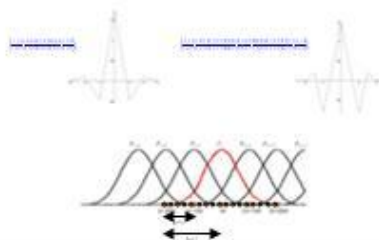
$$P f = \sum_{i=0}^n c_i B_i$$

is a reasonable approximation to f .

We fix a grid process the following procedure is for determining c_i .

- Choose a local interval $I = [x_i, x_{i+1}]$ with the property that I intersects the support of B_i and B_{i+1} . Divide the restriction of the space S_2 (this interval I) by S_2 in S_2 (i.e. $S_2 = \text{span}\{B_i, B_{i+1}\}$).
- Choose some local approximation method P_i with the property that $P_i = \text{id}$ for all $g \in S_2$.
- Let f_i denote the restriction of f to the interval I . Then there exist B-spline coefficients $\{c_i\}_{i=0}^n$ such that $P f_i = \sum_{i=0}^n c_i B_i$.
 Note that $c_i = 0$ if $i \notin \{0, 1, \dots, n\}$ since $\text{span}\{B_i\}$ intersects I .
- Set $c_i = 0$.

Weights : uniform data case



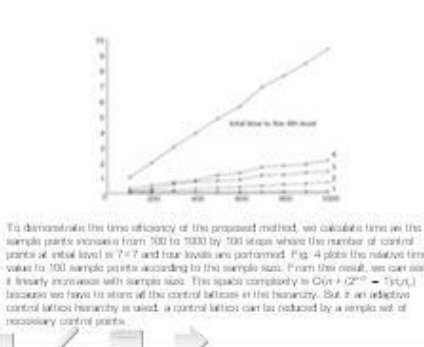
Applications



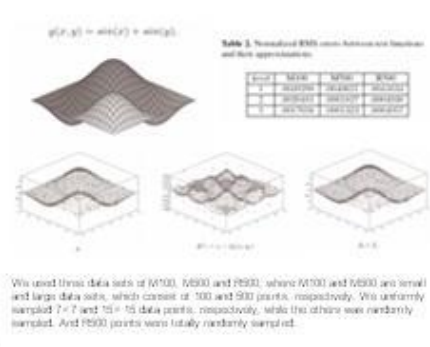
Given a test function $g(x)$, we first sampled data points from it and applied to the algorithm to obtain an approximation function f . The difference between g and f is then measured by computing the normalized RMS (root mean square) error which is divided the RMS error by the difference of maximum and minimum values of g between the function values on a dense grid.

$$RMS = \sqrt{\frac{\sum_{i=1}^N (g(x_i) - f(x_i))^2}{(N+1)}}$$

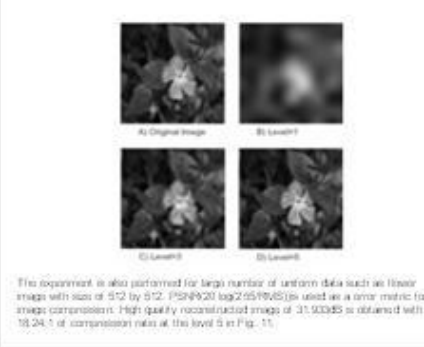
Level	m	n	err	err
0	100	100	0.000000	0.000000
1	100	100	0.000000	0.000000
2	100	100	0.000000	0.000000
3	100	100	0.000000	0.000000
4	100	100	0.000000	0.000000
5	100	100	0.000000	0.000000
6	100	100	0.000000	0.000000



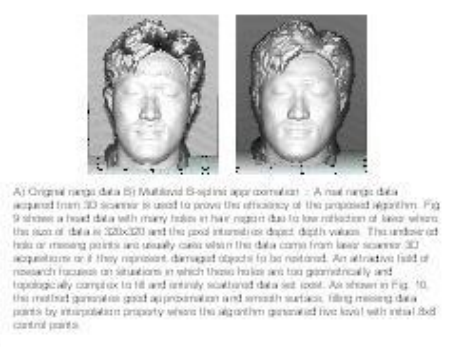
To demonstrate the time efficiency of the proposed method, we calculate time as the sample points increase from 100 to 1000 by 100 steps where the number of control points of initial level is 7*7 and four levels are performed. Fig. 4 plots the relative time values to 100 sample points according to the sample size. From this result, we can see it linearly increases with sample size. The space complexity is $O(n) + O(2^k) = O(n)$, because we have to store all the control lattices in the hierarchy. But if an adaptive control lattice hierarchy is used, a control lattice can be reduced by a simple set of necessary control points.



We used three data sets of M100, M500 and P500, where M100 and M500 are small and large data sets, which consist of 100 and 500 points, respectively. We uniformly sampled 7*7 and 10*10 data points, respectively, while the others were randomly sampled. And P500 points were totally randomly sampled.



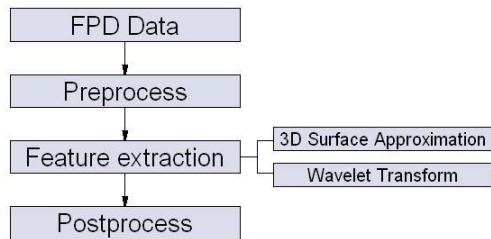
The experiment is also performed for large number of uniform data such as flower image with size of 512 by 512. PSNR@20 log2(255/195) is used as a error metric for image compression. High quality reconstructed image of 31.93385 is obtained with 18.24% of compression ratio at the level 5 in Fig. 11.



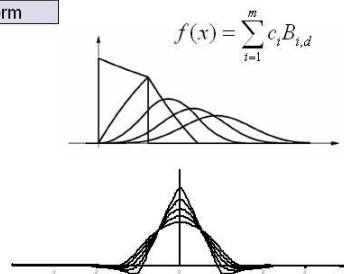
(A) Original range data (B) Multilevel B-spline approximation - A real range data acquired from 3D scanner is used to prove the efficiency of the proposed algorithm. Fig. 9 shows a head data with many holes in hair region due to low resolution of laser where the size of data is 320x320 and the poor intermediate depth depth values. The universe of hole or missing points are usually cases when the data come from laser scanner 3D acquisition or if they represent damaged objects to be restored. An attractive field of research focuses on situations in which these holes are less geometrically and topologically complex to fill and entirely scattered data set (see). As shown in Fig. 10, the method generates good approximation and smooth surfaces, filling missing data points by interpolation properly where the algorithm generated five levels with total 80 control points.



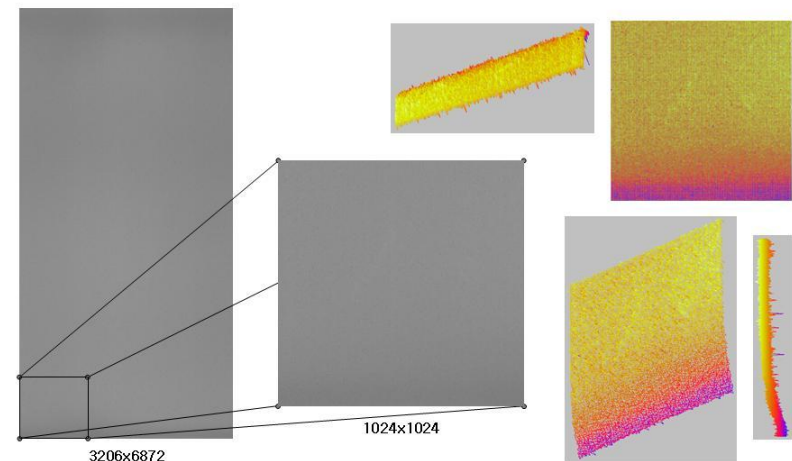
Work flow



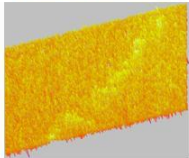
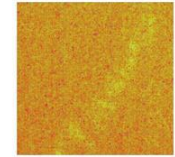
- 3D Surface Approximation
- Polynomial
 - B-spline
 - Psi basis(edge enhancement, CAGD2005 yoon)
 - Exponential spline
- Global vs Local
- Cross Validation
 - Thresholding(height vs area)



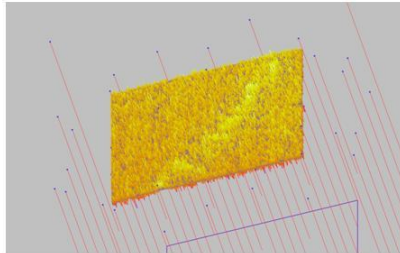
BLU 얼룩불량 377_6317.bmp



Cubic B-spline approximation

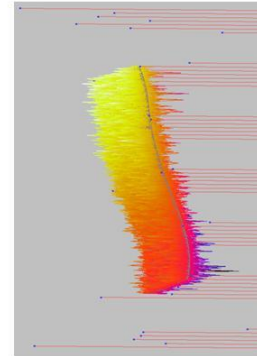


256x256 bmp image

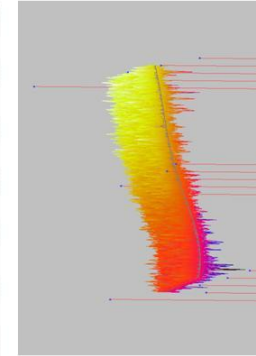


Cubic B-spline approximation with 7x7 control points

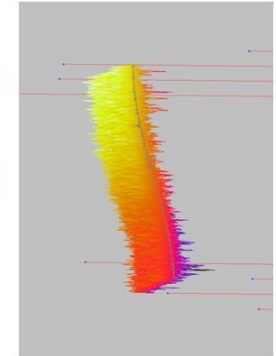
Number of control points



7x7 control points



5x5 control points



4x4 control points

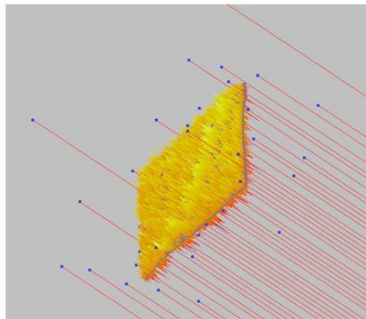


lbg@dongseo.ac.kr

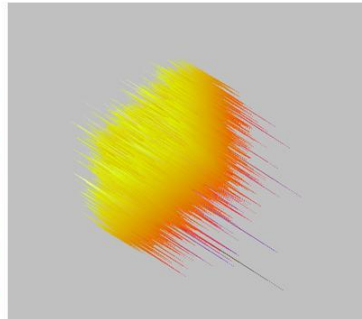


lbg@dongseo.ac.kr

Difference image

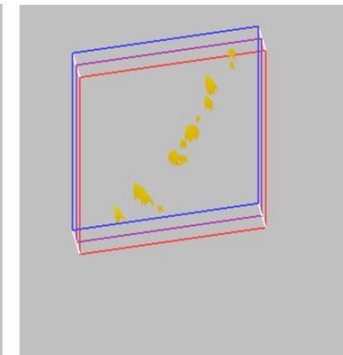
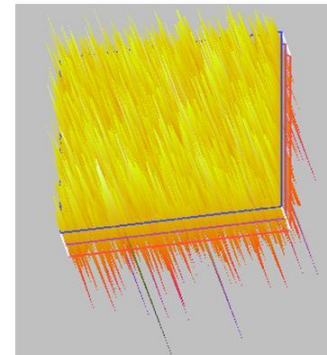


Cubic B-spline approximation with 7x7 control points



Difference bitmap image data

Mura detection filter



with mura detection filter

A WAVELET BASED FLAT PANEL DISPLAY DEFECT DETECTION



Wave 2006, July 10-14, 2006, EPFL Lausanne, Swiss
 Byung-Gook Lee, Joon-Jae Lee, Hoon Yoo, Yeon-Ju Lee, Jungho Yoon
 lbg@dongseo.ac.kr http://kowon.dongseo.ac.kr/~lbg/



Objectives

- Defect Detection of Flat Panel Display

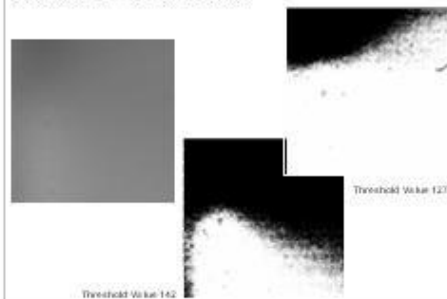
Problems

- Uneven illumination due to self radiation
- High frequency noise inherent in images

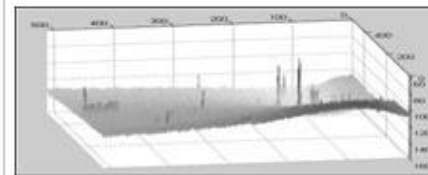
The Proposed Method

- Surface approximation based approach using wavelet multiresolution

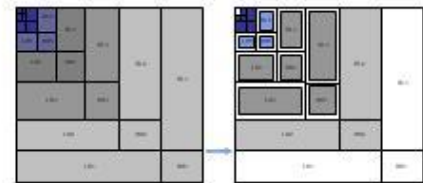
Uneven illumination



Idea for uneven illumination compensation



Wavelet Representation



- Field of automatic inspection and FPD products
 Why do we need the automatic inspection of FPD?
 What is the FPD products?

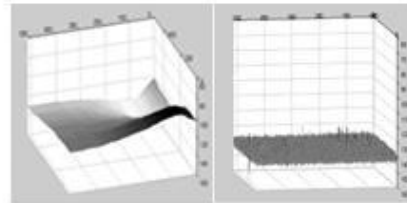
- Approach the points and - locations
 Analyze the defects in FPD
 How can we solve the problems?
 Understand the algorithms, our lots by imposed

- Multi-layered structure
 High probability of defect occurrence at the inside of panel
 Needs of high clearance level

- The array of many integrated semi-conductor
 detect the amount of light from light source
 detect the amount of light which are emitted by itself

- Products
 TFT-LCD, PDP, OEL, OLED, CELL, SLM, FILM, etc

Elimination parts for compensation



Compensation approach

$$F(x) = (HH_1 + HL_1 + LH_1) + (HH_2 + HL_2 + LH_2) \dots$$

$$(LL_1 + HH_2 + HL_2 + LH_2)$$

$$F_d(x) = HH_1 + HL_1 + LH_1$$

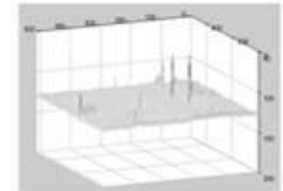
$$F(x) = LL_1$$

$$F_d(x) = (HH_{2n} + HL_{2n} + LH_{2n}) + (HH_{2n+1} + HL_{2n+1} + LH_{2n+1}) +$$

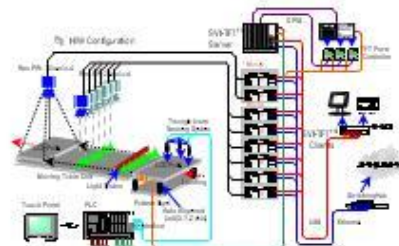
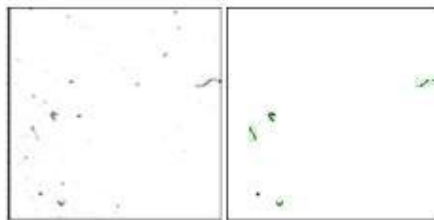
$$(HH_{2n+2} + HL_{2n+2} + LH_{2n+2})$$

$$F'(x) = F(x) - F_d(x) - F_d(x) - F_d(x)$$

Compensated image result



Detected result by simple threshold



Performance

Input size	CPU - 3GHz, Memory - 1GB				
	1MB	16.8MB	19.5MB	22MB	53MB
Procedure					
Wavelet Decomposition	0.075	0.328	0.375	0.437	1.092
Wavelet Synthesis	0.032	0.328	0.375	0.438	1.031
Thresholding	0.070	0.202	0.298	0.38	0.85
Sub-analysis	0.063	1.663	1.823	2.021	0.20
Total	0.126	2.201	2.869	3.296	9.153

Conclusion and further research

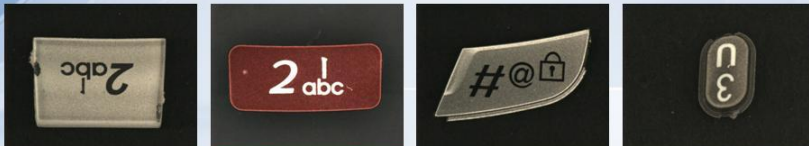
- Mathematical analysis using surface approximation for illumination compensation
- Performance
 Accuracy, Speed, Reliability
- General method for various defect types





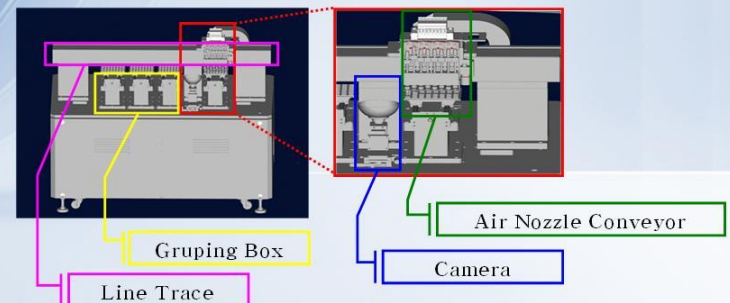
Keypad Inspection System of Cellular Phone

Seung Il Han, Du Cheol Gang, Byung Gook Lee, Joon Jae Lee
Graduate School of Design & IT, Dongseo University
{ted12, newsephiro, lbg, jjlee}@dongseo.ac.kr



Inspection Machine

- Part
 - Air Nozzle Conveyor
 - Camera
 - Grouping Box
 - Line Trace



Inspection Object

- Color Grade



- KeyButton Defect Detection

- Font Defect Detection
- Scratch Detection



Font Defect

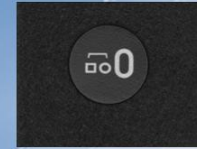


Scratch

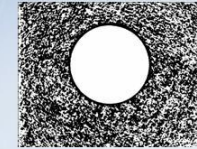
GGIV07_14-17 August 2007, Bangkok, Thailand

Keypad Inspection System of Cellular Phone

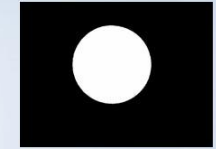
KeyButton & Font Area Detection



Otsu Threshold



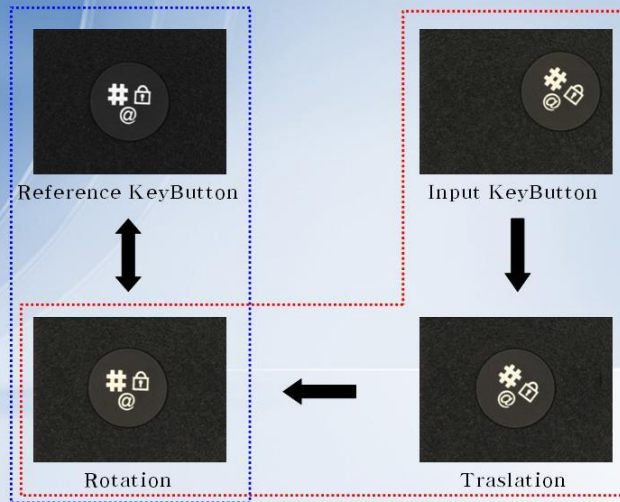
Blob Analysis



GGIV07_14-17 August 2007, Bangkok, Thailand

Keypad Inspection System of Cellular Phone

Affine Transformation

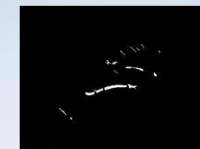


Scratch & Font Defect Detection

- Scratch Detection

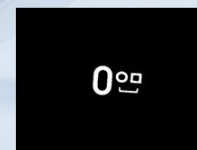


Input KeyButton

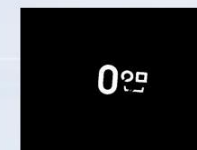


Scratch

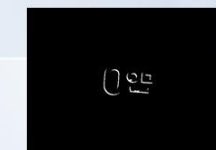
- Font Defect Detection



Reference KeyButton



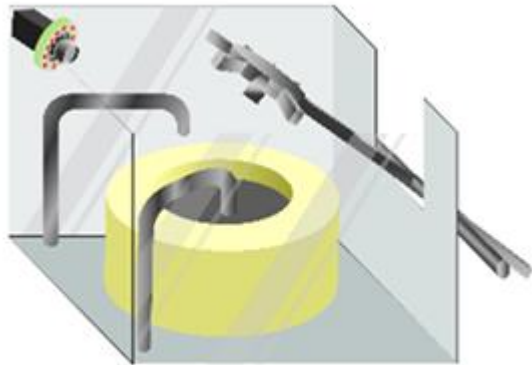
Input KeyButton



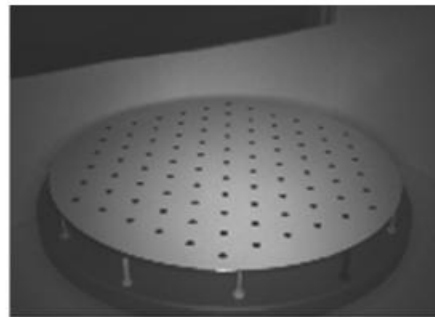
Font Defect Detection

Development of Vision System for Wafer Position Recognition using Radial Shape Calibrator

lbg@dongseo.ac.kr 2008.12.03

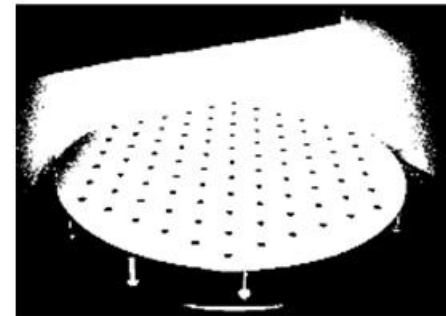


System Overview

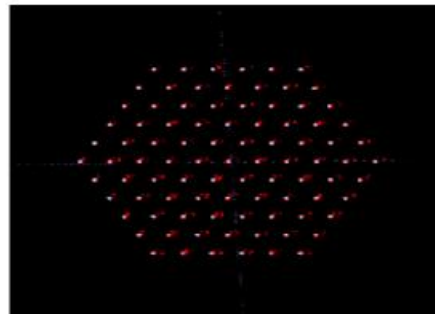


$$x_p = \frac{m_0x_u + m_1y_u + m_2}{m_6x_u + m_7y_u + 1}$$
$$y_p = \frac{m_3x_u + m_4y_u + m_5}{m_6x_u + m_7y_u + 1}$$

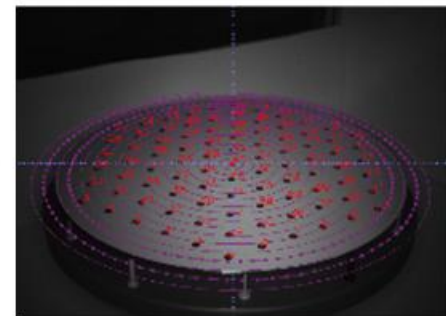
Binary Image



Radial Shape Calibrator



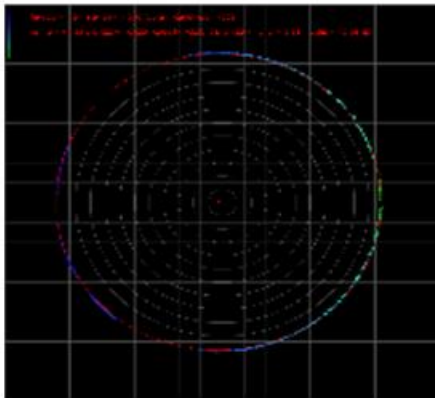
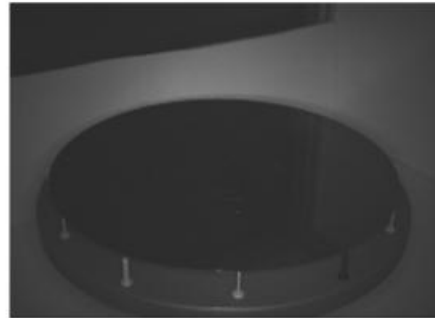
Calibration



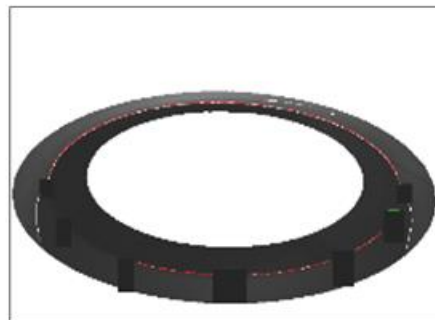
Numbering



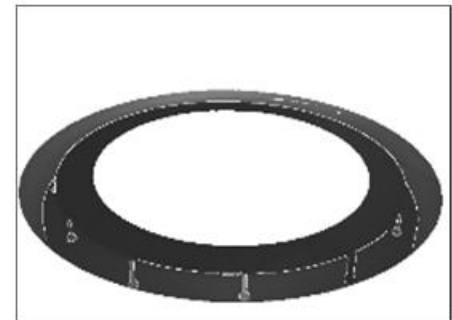
Digital Area Scan Camera



Wafer Circle Estimation



Wafer Edge Detection



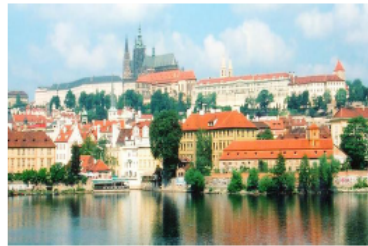
Edge Detection

Image Deformation using Radial Basis Function Interpolation

Jung Hye Kwon, Byung Gook Lee, Jungho Yoon, Jun Jae Lee

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 yoon@ewha.ac.kr, joonlee@kmu.ac.kr

The 17-th International
 Conference on Computer
 Graphics, Visualization and
 Computer Vision
 February 2-5, 2009, Plzen,
 Czech Republic



Radial Basis Function

- A function $f: \mathbb{R}^d \rightarrow \mathbb{R}^d$ is known only at a set of discrete points $U := \{u_1, u_2, \dots, u_n\}$ and desired function values $V := \{v_1, v_2, \dots, v_n\}$, we can define

$$S_{f,U}(u) = \sum_{i=1}^n \alpha_i \phi(\|u - u_i\|) + \sum_{j=1}^m \beta_j p_j(u)$$

with the constraints

$$\sum_{i=1}^n \alpha_i p_j(u_i) = 0, j = 1, 2, \dots, m$$

Here, $p_j(u) \in \Pi_r^d$ is the space of polynomial of total degree r in d spatial dimensions

Image Deformation

- As one field of computer graphics
- The deformation method of changing image to be wanted by user
 - Used in the field of computer animation, morphing and medical image
- To perform deformation the user selects some set of handle
 - Points, lines, or grids

Previous Deformation Techniques

- Mesh base method
 - T. Igarashi, T. Moscovich, and J. F. Hughes, "As-rigid-as-possible shape manipulation.", ACM Trans. Graph 2005, 24, 3, pp 1134-1141 (2005).
 - Y. Weng, W. Xu, Y. Wu, K. Zhou, B. Guo, "2D shape deformation using nonlinear least squares Optimization.", The visual computer, pp 653-660(2006).
- Approximation method
 - S. Schaefer, T. McPhail, J. Warren, "Image deformation using moving least squares.", Proceedings of ACM SIGGRAPH, pp. 533-540 (2006).
 - N. Arad, N. Dyn, D.Reisfeld, Y.Yeshurun, "Image warping by radial basis functions :Application to facial expressions", Computer Vision Graphics and Image Processing, p.p 161-172 (1994).

Image deformation using RBF

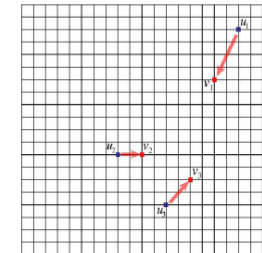
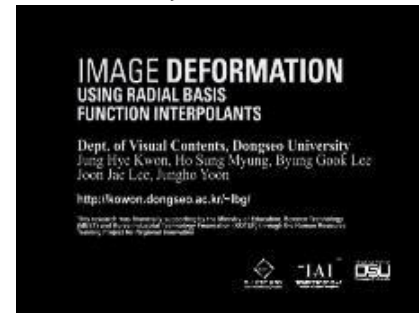
- Since constructing a deformed image from an original one is a mapping from \mathbb{R}^2 to \mathbb{R}^2 , we have given two sets of 2-dimensional data $U := \{u_1, u_2, \dots, u_n\}$ and deformed position $V := \{v_1, v_2, \dots, v_n\}$. We solve for the radial basis function interpolation $S_{f,U}(u)$, satisfying

$$S_{f,U}(u_i) = v_i - u_i, \quad i = 1, 2, \dots, n.$$

where $v_i - u_i$ is difference vector v .

Finally, we obtain a deformed position

$$v = u + S_{f,U}(u)$$



Definition of pictogram

- The pictogram is a compound word where means the picture and a telegram.
- The pictogram delivers information easily & quickly.

pictogram = picture + telegram



Functions of pictogram

Guidance Function

Public people understand some information easily.



Command Function

The human being must observe.



A Study on Effective Visual Communication Method with the 'Pictomation' Contents in Augmented Reality Environment

2009.07.15 | DEPT. OF VISUAL CONTENTS, DONGSEO UNIVERSITY
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Conditions of pictogram

Must read quickly, easily and exactly.

Must deliver the meaning easily.

Must be considered the brief expression and an esthetic characteristic.

Must be induced the act of consumer to original intent.

Must be popular, public and convenient to use.

A Study on the 'PICTOMATION' Contents Effective Visual Communication Method in Augmented Reality Environment

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Hosung Myung, Namseok Choi, Hohwan Shin,
Eunkyung Jung, Byungook Lee, Hyungwoo Kim
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Pictomation using ARToolkit



- A Marker pattern input
- B Video output (computer graphics area)
- C Video output (real world area)

Proposal of the pictomation

Visual elements of pictogram should be expressed and reconstituted in common experience, not creation a new one.



'A MAN IS DRINKING WATER'
Visual elements : 'Man', 'Water' : [noun]

'A MAN IS DRINKING WATER'
Animation elements : 'Drinking' : [verb]

First, I abstracted 'man' and 'water' from linguistic element in 'a man is drinking water' and expressed it as visual elements. Second, I made an animation with behavior elements which is 'drink'.

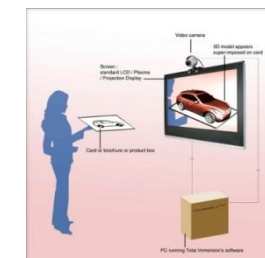
Proposal of the pictomation

Pictomation = Pictogram + Animation



['DRINKING FOUNTAIN' PICTOMATION]

Augmented Reality



AR(augmented reality) provide vivid 3d information
[\[http://www.mini.de/webcam\]](http://www.mini.de/webcam)

Thanks

**Lee Byung Gook, Professor
Division of Computer Information Engineering
Dongseo University**

**<http://kowon.dongseo.ac.kr/~lbg/>
e-mail : lbg@dongseo.ac.kr**



uBiquitous fRontier !

fRontier in uBiquitous Computing

fRontier in uBiquitous Education

fRontier in uBiquitous Culture

Background Modeling

Bayesian Modeling of Dynamic Scenes for Object Detection

IEEE TRANSACTIONS ON PATTERN ANALYSIS AND MACHINE INTELLIGENCE, VOL. 27, NO. 11, NOVEMBER 2005
 Yaser Sheikh, and Mubarak Shah by lbg@dongseo.ac.kr 2009.02.25

Background $\varphi_b = \{y_1, y_2, \dots, y_n\}, y = (r, g, b, x, y) \in \mathbb{R}^5$

Foreground $\varphi_f = \{z_1, z_2, \dots, z_m\}$

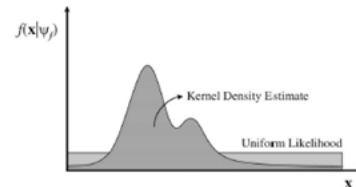
$$P(x | \psi_b) = \frac{1}{n} \sum_{i=1}^n \varphi_H(x - y_i)$$

$$P(x | \psi_f) = \alpha \gamma + (1 - \alpha) m^{-1} \sum_{i=1}^m \varphi_H(x - z_i)$$

d-variate Gaussian density

Likelihood ratio classifier $\tau = -\ln \frac{P(x | \psi_b)}{P(x | \psi_f)}$

$$\varphi_H^{(N)}(x) = |H|^{-1/2} (2\pi)^{-d/2} \exp\left(-\frac{1}{2} x^T H^{-1} x\right)$$



Technical Solution: Robot PTZ camera with Magnetic fence protection system

How does it work?

1) This system can detect and guard specifically interlocking with Robot CCTV, broadcasting equipment and light device by installing magnetic sensor cable around the outer wall guarding area, and analyzing alarm and sound information when intrusion occurs from the outside.

2) Each 150M-divided alarm I/O signal connected to Robot PTZ camera to use close-up intruders image display with recording alarm automatically.

3) Robot PTZ camera move to intruder detecting area with close-up intruder's image, recording alarm, & return to four operation of 20-pre-set zone automatically.

4) Control Room

- Close-up real time image display with PTZ control of intruder detecting zone.
- Automatic recording alarm & command at intruders detection.
- Built-in intruders motion detection, tracking, recording, alarm each pre-set zones by Intruder- For sight 1 Software program (optional) (2) Pre-set (Group) Zones.
- Same time above all conditions connect to control room, master control room, your recommended office by local or internet network line (TCP/IP).

5) With real-time video assessment (Using a PCA), an operator can send Border Patrol Agents to the intrusion spot automatically (Mobile phone software program by F.O.C.).

SuperResolution

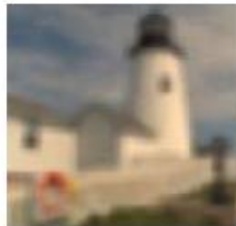
Real World Scene



Motion Effect



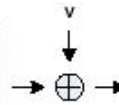
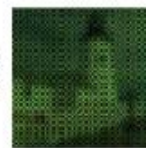
Camera Blur Effect



Down Sampling Effect



Color Filtering Effect



Noisy, Blurred, Down Sampled, Color Filtered, Outcome Y



Fast and Robust Multiframe Super Resolution

IEEE TRANSACTIONS ON IMAGE PROCESSING, VOL. 15, NO. 10, OCTOBER 2004
Sina Park, M. Dik Robinson, Michael Elad, and Payman Milanfar
by lbg@dongseo.ac.kr 2009.02.20

$$\underline{Y}_k = D_k H_k F_k \underline{X} + \underline{V}_k$$

$$\underline{X} = \underset{\underline{X}}{\text{ArgMin}} \left[\sum_{k=1}^N \|D_k H_k F_k \underline{X} - \underline{Y}_k\|_p \right] \quad \underline{X} = \underset{\underline{X}}{\text{ArgMin}} \left[\sum_{k=1}^N \|D_k H_k F_k \underline{X} - \underline{Y}_k\|_p + \lambda \mathcal{R}(\underline{X}) \right]$$

$$Y_r(\underline{X}) = \|\mathbf{r}\underline{X}\|_1, \quad Y_{TV}(\underline{X}) = \|\nabla \underline{X}\|_1, \quad Y_{SPV}(\underline{X}) = \sum_{l=1}^p \sum_{m=0}^{p-l} \alpha^m \mathcal{H}[\|\underline{X} - S_l^l S_r^m \underline{X}\|]$$

$$\underline{X}_{n+1} = \underline{X}_n - \beta \left(\sum_{k=1}^N F_k^T H_k^T D_k^T \text{sign}(D_k H_k F_k \underline{X}_n - \underline{Y}_k) \right) + \lambda \sum_{l=1}^p \sum_{m=0}^{p-l} \alpha^m \mathcal{H}[\mathcal{I} - S_r^m S_l^l] \text{sign}(\underline{X}_n - S_l^l S_r^m \underline{X}_n) \quad \text{Robust Method}$$

$$\underline{X}_{n+1} = \underline{X}_n - \beta (H^T A^T \text{sign}(A H \underline{X}_n - A Z)) + \lambda \sum_{l=1}^p \sum_{m=0}^{p-l} \alpha^m \mathcal{H}[\mathcal{I} - S_r^m S_l^l] \text{sign}(\underline{X}_n - S_l^l S_r^m \underline{X}_n) \quad \text{Fast Robust Method}$$

U-Pointer 전자 판서 시스템

Byung-Gook Lee lbg@dongseo.ac.kr

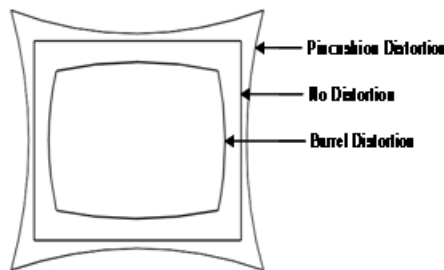
2008.12.29~2009.02.11



- U-Pointer Calibration
- Calibration을 위한 효율적인 feature point 위치 선정
- 광각렌즈 적용 Calibration 오차 보정
- 단 초점 projector U-Pointer의 좌표 매핑 알고리즘
- 유연한 판서를 위한 세부 알고리즘

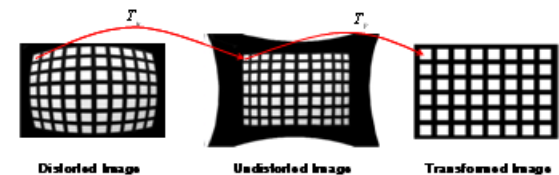
Lens Distortion

어안렌즈에 따라 생기는 왜곡의 종류



Zoom Lens Distortion

줌 렌즈(Zoom Lens)를 사용하면 Pincushion Distortion이 생기고, 어안 렌즈(Wide Angle Lens)를 사용하면 Barrel Distortion이 생긴다. 따라서 기존의 방법과 다르게 렌즈의 왜곡을 먼저 보정한 후 이미지의 왜곡을 보정하면 좀 더 정확한 결과가 나올 것이다. 아래의 그림은 렌즈의 왜곡 보정과 이미지의 보정을 도식화 한 그림이다.



Calibration

위와 같은 과정을 거치기 위해서는 아래와 같은 수식을 사용한다. 아래의 식을 사용하기 위해서 θ set을 구하여야 한다.

$$I(i,j) = I_f(x(\theta,i,j), y(\theta,i,j))$$

θ set은 그림 2의 I_x 와 I_y 에서 각각 구해야 한다. 먼저 I_x 를 구하는 식은 아래와 같다.

$$\begin{aligned} x_s &= C_x + (x_d - C_x) / f_1 (r_1^2) \\ &= C_x + (x_d - C_x) (1 + k_1 r_1^2 + k_2 r_1^4 + k_3 r_1^6) \\ y_s &= C_y + (y_d - C_y) / f_2 (r_2^2) \\ &= C_y + (y_d - C_y) (1 + k_1 r_2^2 + k_2 r_2^4 + k_3 r_2^6) \\ r_1^2 &= (x_d - C_x)^2 + (y_d - C_y)^2 \end{aligned}$$

여기서 이미지의 왜곡 중심 (C_x, C_y)와 K 에 관한 내용을 모르기 때문에 이를 $\theta^k = \{C_x, C_y, K_1, K_2, K_3\}$ 로 정의 한다.

I_x 를 구하는 식은 아래와 같다. 우리는 아래의 식에서 m 값을 모르기 때문에 $\theta^m = \{m_0, m_1, m_2, m_3, m_4, m_5, m_6, m_7\}$ 로 정의 한다.

$$\begin{aligned} M &= \begin{bmatrix} m_0 & m_1 & m_2 \\ m_3 & m_4 & m_5 \\ m_6 & m_7 & 1 \end{bmatrix} \\ x_p &= \frac{m_0 x_s + m_1 y_s + m_2}{m_3 x_s + m_4 y_s + 1} \\ y_p &= \frac{m_5 x_s + m_6 y_s + m_7}{m_3 x_s + m_4 y_s + 1} \end{aligned}$$

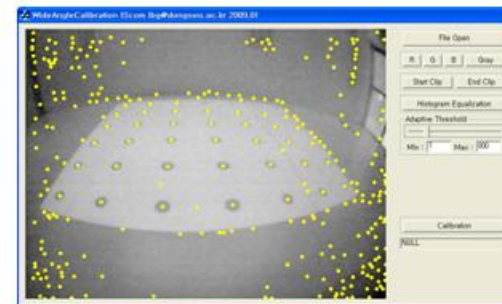
위에서 구한 θ^k 와 θ^m 의 합집합을 θ 라고 정의 한다. 따라서 $\theta = \theta^k \cup \theta^m$ 로 정의됨을 알 수 있다. 그리고 아래의 수식을 이용하여 error가 가장 최소가 될 때의 값을 획득하여 Calibration 하게 되면 그림 2와 같은 이미지 보정을 할 수 있다.

$$\begin{aligned} e_{1k} &= x_p(\theta, x_{0k}, y_{0k}) - x_{1k} \\ e_{2k} &= y_p(\theta, x_{0k}, y_{0k}) - y_{1k} \\ E(\theta) &= \sum_{k=1}^N ((e_{1k})^2 + (e_{2k})^2) \\ \theta &= \text{argmin}_{\theta} E(\theta) \end{aligned}$$

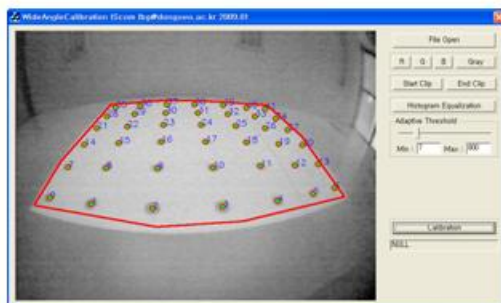
Calibrator Image



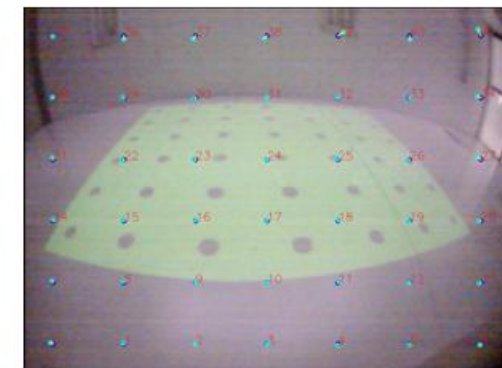
Blob Analysis



Clipping & Numbering



Calibration Result



Virtual Interactive Board U-Pointer

ICCommunications Co., Ltd.

Wants to have an interactive electronic board on any wall in your room? Place the U-Pointer beside the beam projector and connect it to a computer and the wall of your choice becomes an interactive electronic board. It is a Virtual Interactive Board.



Main Feature of U-Pointer

Interaction with PC via the projected screen
 -Click, double click and drag function of conventional mouse is available by the U-Pointer. You can control PC from the projected screen interactively. It enables the freedom of a window presentation in a remote or conference, and the cost of the projected screen is up to 100 million.

Easy Installation

-Place the U-Pointer on top of the projector and connect it to the PC via a USB cable.
 -Align the U-Pointer on the beamed screen and adjust its lens.
 -Light sample along with easy calibration window. The U-Pointer is to be presentation perfect.



Accurate Pen Work
 -The high resolution of the U-Pointer provides the capability of writing small characters, that those written with a white board.
 -The fast response time and wide DR range per second of writing are good job, the same holding if you use using a white board.



Powered by MMS Multimedia Interactive Board Software
 -Choosing on the beamed presentation screen will increase your presentation effectiveness drastically. The need to transfer the type of the audience will always be fulfilled on the screen as the previous. Screen names can be distributed in computer format following the Presentation.

U-Pointer		Applications	
Manufacturer	ICCommunications Co., Ltd. (Korea, Seoul)	Education	U-Pointer enables expensive multi-media class needed for an electronic board function in a relatively small.
Model	U-Pointer	Business	The System can be used immediately without the need to draw on a sign. The feature is available in a multi-media system and can be used as a multi-time or concerning on an education.
Power Source	USB Cable	Business	An interactive presentation is possible without breaking eye contact in conference and/or seminars.
Resolution	1024x768 pixels	Business	In branching sectors or meetings that require intensive reports or user their presentations, they will be distributed to presentation.
Control	U-Pointer	Business	Any notes from board can be copied and distributed in computer format at a short time.
Resolution	1024x768 pixels		
Model	U-Pointer		
Power Source	USB Cable		

A New Class of Non-Stationary Interpolatory Subdivision Scheme based on Exponential Polynomials

Yoo-Joo Choi¹, Yeon-Ju Lee¹, Jung-ho Yoon¹, Byung-Gook Lee¹, Young J. Kim¹
¹Seoul University of Venture and Information, ²Ewha Womans University, ³Dongseo University

INTRODUCTION

- The Butterfly scheme, which is a stationary interpolatory scheme based on cubic polynomial interpolation, may not accurately reproduce highly oscillatory triangular mesh data. It has been shown that a non-stationary subdivision scheme based on exponential or trigonometric polynomials with a suitable frequency factor works more effectively on highly oscillatory signals than stationary interpolatory scheme based on polynomials.
- We introduce a new class of non-stationary interpolatory subdivision schemes that can exactly reproduce a complicated, parametric surface including exponential polynomials in the sense of complex numbers. In our scheme, exponential polynomials constitute a shift-invariant space and the mask of our subdivision scheme is constructed in such a way as to find the values of the exponential polynomials that correspond to the initial control points.

METHODS

Basic Interpolatory Subdivision Scheme

Construction Rules

• **Parametric surface** $F(u,v)$ on a planar parametric domain $\Omega \subset \mathbb{R}^2$ can contain polynomial, trigonometric and exponential functions.

• **Shift invariant space S :**

$$f \in S \text{ implies } f(-\alpha) \in S, \alpha \in Z \tag{1}$$

$$\phi(u,v) = u^{\alpha_1} v^{\alpha_2} e^{\beta_1 u} e^{\beta_2 v}, (u,v) \in \Omega \subset \mathbb{R}^2, \text{ where } \alpha_i = 0, \dots, \mu \text{ for some non-negative integer } \mu \text{ and complex numbers } \beta_i (i=1,2). \tag{2}$$

$$S = \text{span}\{\phi_n(u,v) \mid n = 1, \dots, N\}$$

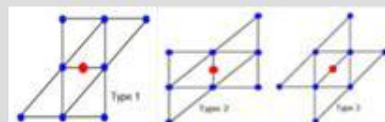
$$\phi_n = (p2^{-k}) \sum_{\alpha \in \mathbb{Z}^2} a_{\alpha}^{(k)} \phi_n(t2^{-k}), \phi_n \in S, k = 0, 1, \dots, \tag{3}$$

where $p/2$ is the insertion point in the triangulation at level 0 and κ is its corresponding stencil.

Example (Sphere and Torus)

$$S := \text{span}\{\sin u, \cos u, \sin v, \cos v, \sin u \sin v, \cos u \cos v, \sin u \cos v, \cos u \sin v\}$$

The three types of refinement rule are obtained by solving the linear system of Eq. 3 using the butterfly stencil.

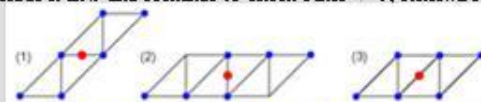


Subdivision stencils based on butterfly shapes

Reconstruction of Complicated Surfaces

Finding the shift Invariant Space in the smallest dimension

- Initially, we set S to be the same as span a finite collection of functions B , whose elements generate F via a linear combination.
- We pick an element f from S and perform a constant shifting of f as shown in Eq. 1.
- We enumerate all the monomials f^i constituting $f(-\alpha)$.
- For each f^i , if it can be generated by the current S , then we do not include it in S and continue to check other f^i 's; otherwise we add it to S .
- Repeat between 2 and 4 until there is no possible new addition to S .
- Finally, we have the shift invariant space $S := \text{span } S$.



Type 1, 2 and 3 stencils for a Möbius strip

Stencil Generation Algorithm

- We construct a stencil starting from a newly inserted point p . First, we choose two stencil vertices (say v_1 and v_2) connected to p and continue to search for other stencil vertices by expanding v_1 and v_2 to their neighborhood while keeping the stencil shape symmetric.
- the n -ring neighbors of v are defined as vertices that are reachable from v by traversing no more than n edges in the mesh.
- This search process continues until the associated matrix B satisfies $\dim B = \dim S$.

RESULTS



Reconstruction of a sphere and a torus



(a) our scheme (b) the Butterfly scheme
Exact reconstruction of a torus.

	initial mesh	level 1	level 2	level 3
möbius strip				
klein bottle				
figure-8 klein bottle				
sea shell surface				
fish surface				
superellipsoid				

Reconstruction of complicated surfaces.

CONCLUSION

- The shift-invariant property ensures that local weights corresponding to local control points are invariant, regardless of their locations, which ultimately enables parametric surfaces to be generated exactly.
- A complicated surface generated from both polynomials and trigonometric polynomials can be exactly reproduced from a set of coarse initial points

A New Class of Non-Stationary Interpolatory Subdivision Scheme based on Exponential Polynomials

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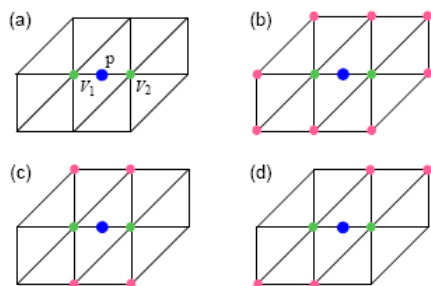


Fig. 5. Type 1 stencil for a Möbius strip. (a) The newly inserted point p is colored blue and the two green points are chosen as the immediate neighbors (v_1, v_2). (b) The one-ring neighbors of v_1, v_2 are colored pink. (c) A candidate stencil, turns out to be invalid. (d) A valid stencil.

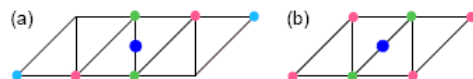


Fig. 6. Type 2 and 3 stencils for a Möbius strip.

Example 2. (Möbius strip) The parametric equation $F(u, v)$ for Möbius strip is given by

$$\begin{aligned} x(u, v) &= a \cos u + v \cos(u/2), \\ y(u, v) &= a \sin u + v \cos(u/2), \\ z(u, v) &= v \sin(u/2), \end{aligned}$$

where $0 \leq u \leq 2\pi$, $-w \leq v \leq w$, and w and a are constants.

Then the space that generates the parametric surface with the smallest dimension is

$$B := \{ \sin u, \cos u, v \sin(u/2), v \cos(u/2) \},$$

and the corresponding shift-invariant space S that generates $F(u, v)$ is

$$S := \text{span} \{ \sin u, \cos u, \sin(u/2), \cos(u/2), v \sin(u/2), v \cos(u/2) \}.$$

RESULTS

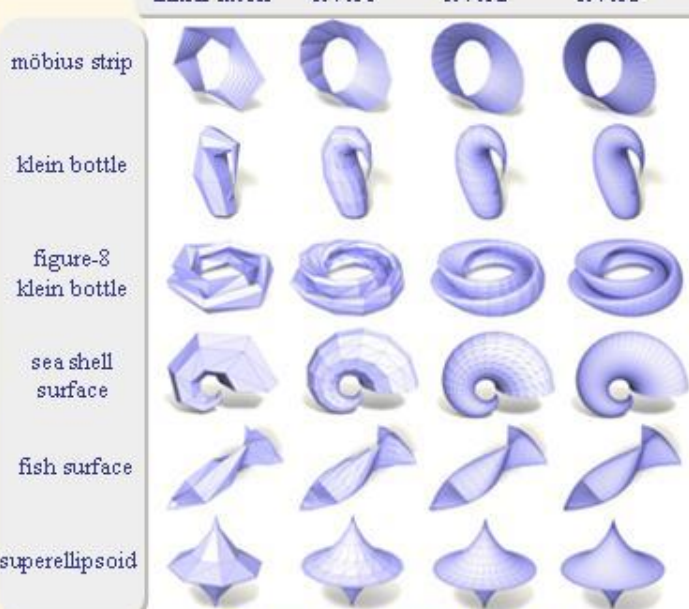


Reconstruction of a sphere and a torus



(a) our scheme (b) the Butterfly scheme
Exact reconstruction of a torus.

initial mesh level 1 level 2 level 3



Reconstruction of complicated surfaces.

CONCLUSION

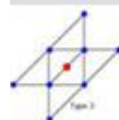
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may not accurately
 based on exponential
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complicated, parametric
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and exponential functions.

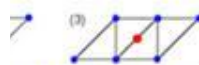
- (1)
- (2)
- (3)



butterfly shapes

a linear combination.

other f_i 's, otherwise



a möbius strip

by v_j and v_j connected
 keeping the stencil

edges in the mesh.

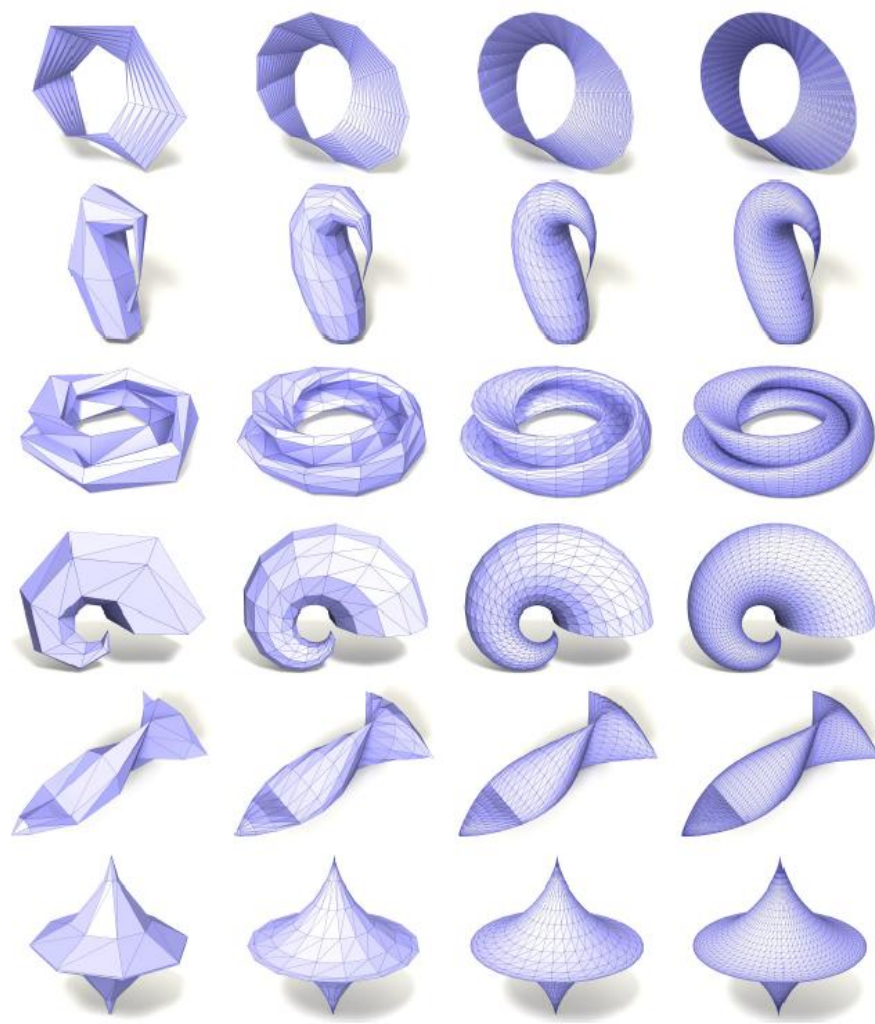
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where $\alpha_i = 0, \dots, \mu$ for some non-negative integer μ and complex numbers $\beta_i (i=1,2)$.

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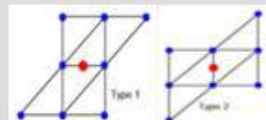
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where $p/2$ is the insertion point in the triangulation at level 0 and κ is its corresponding stencil.

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$$S := \text{span}\{\sin u, \cos u, \sin v, \cos v, \sin u \sin v, \cos u \cos v, \sin u \cos v, \cos u \sin v\}$$

The three types of refinement rule are obtained by solving the linear system of Eq. 3 using the butterfly stencil.

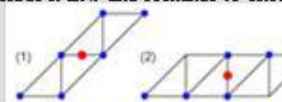


Subdivision stencils based on

Reconstruction of Complicated Surfaces

Finding the shift Invariant Space in the smallest dimension

- Initially, we set S to be the same as span a finite collection of functions B , whose elements generate F via
- We pick an element f from S and perform a constant shifting of f as shown in Eq. 1.
- We enumerate all the monomials f^i constituting $f(-\alpha)$.
- For each f^i , if it can be generated by the current S , then we do not include it in S and continue to check we add it to S .
- Repeat between 2 and 4 until there is no possible new addition to S .
- Finally, we have the shift invariant space $S := \text{span } S$.



Type 1, 2 and 3 stencils for

Stencil Generation Algorithm

- We construct a stencil starting from a newly inserted point p . First, we choose two stencil vertices (s_1 to p and continue to search for other stencil vertices by expanding v_1 and v_2 to their neighborhood while shape symmetric.
- the n -ring neighbors of v are defined as vertices that are reachable from v by traversing no more than n edges.
- This search process continues until the associated matrix B satisfies $\dim B = \dim S$.

polynomials can be exactly reproduced from a set of coarse initial points

Stationary Subdivision Schemes Reproduction Polynomials

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Case 1: L is even, i.e., $L = 2N$.

For the construction of the odd mask, we use the stencil of $L = 2N$ points to reproduce polynomials in $\Pi_{<L}$. That is, the odd mask $\{a_{1-2n}: n = -N + 1, \dots, N\}$ is obtained by solving the linear system:

$$p_\ell\left(\frac{1}{2}\right) = \sum_{n=-N+1}^N a_{1-2n} p_\ell(n), \quad \ell = 1, \dots, L, \quad (4)$$

where p_1, \dots, p_L is a basis of $\Pi_{<L}$. Obviously, there is a unique solution of the linear system (4), and it is exactly the same as the odd mask of the L -point Deslauniers–Dubuc scheme. Next, for the construction of the even mask, we use the stencil of $L + 1 = 2N + 1$ points to reproduce polynomials in $\Pi_{<L}$. That is, the even mask $\{a_{2n}: n = -N, \dots, N\}$ is obtained by solving the linear system:

$$p_\ell(0) = \sum_{n=-N}^N a_{2n} p_\ell(n), \quad \ell = 1, \dots, L. \quad (5)$$

This is an underdetermined system of $L + 1$ unknowns in L equations so that there is one degree of freedom which will be used as a tension parameter ω . One may set

$$\omega := a_{2N}. \quad (6)$$

If $\omega = 0$, then the scheme becomes the L -point Deslauniers–Dubuc interpolatory scheme, as we will see later in Example 1. Note that the support of the mask is $\mathbb{Z} \cap [-L, \dots, L]$. As an example, the stencil for the case $L = 4$ is described in Fig. 1(B).

Case 2: L is odd, i.e., $L = 2N + 1$.

On the purpose of obtaining symmetric rules, we employ $L + 1 = 2(N + 1)$ -point scheme reproducing polynomials in $\Pi_{<L}$, and define new (refined) values at $\frac{1}{4}$ and $\frac{3}{4}$ locations between successive old points. Based on this idea, the masks $\{a_{j-2n}: n = -N, \dots, N + 1\}$ with $j = 0, 1$ can be given by solving the linear systems: For the even mask $\{a_{2n}: n \in \mathbb{Z}\}$,

$$p_\ell\left(\frac{1}{4}\right) = \sum_{n=-N}^{N+1} a_{-2n} p_\ell(n), \quad \ell = 1, \dots, L, \quad (7)$$

where p_1, \dots, p_L is a basis of $\Pi_{<L}$. Next, for the odd mask $\{a_{1-2n}: n = -N, \dots, N + 1\}$,

$$p_\ell\left(\frac{3}{4}\right) = \sum_{n=-N}^{N+1} a_{1-2n} p_\ell(n), \quad \ell = 1, \dots, L. \quad (8)$$

Then the obtained subdivision rule satisfies the following relation

$$a_{-2n} = a_{2(n-1)+1}, \quad n = -N, \dots, N + 1,$$

and hence, the basic limit function becomes also symmetric. Each of the systems (7) and (8) consists of $L + 1$ unknowns in L equations and eventually has one degree of freedom which is used as the tension parameter ω . One may set $\omega := a_{2N}$ and $\omega := a_{-2N-1}$ for (7) and (8) respectively. The support of the mask is $\mathbb{Z} \cap [-L - 1, \dots, L]$. As an example, the stencil for the case $L = 3$ is described in Fig. 1(A).

The image shows a technical document page with multiple sections. It contains mathematical derivations, diagrams, and tables. The text is in both Korean and English. The diagrams illustrate the stencil and limit functions for different subdivision schemes. The tables provide numerical data for the schemes.

Figure 1(A): Stencil for the case $L = 3$. The diagram shows the stencil for the even mask $\{a_{2n}\}$ and the odd mask $\{a_{1-2n}\}$. The stencil for the even mask is $\{a_{-2}, a_{-1}, a_0, a_1, a_2\}$ and the stencil for the odd mask is $\{a_{-1}, a_0, a_1, a_2, a_3\}$. The limit function is shown as a symmetric curve.

Figure 1(B): Stencil for the case $L = 4$. The diagram shows the stencil for the odd mask $\{a_{1-2n}\}$ and the even mask $\{a_{2n}\}$. The stencil for the odd mask is $\{a_{-3}, a_{-2}, a_{-1}, a_0, a_1, a_2, a_3\}$ and the stencil for the even mask is $\{a_{-2}, a_{-1}, a_0, a_1, a_2, a_3, a_4\}$. The limit function is shown as a symmetric curve.

Table 1: Stencil for the case $L = 3$.

n	a_n
-3	0
-2	0
-1	0
0	0
1	0
2	0
3	0

Table 2: Stencil for the case $L = 4$.

n	a_n
-4	0
-3	0
-2	0
-1	0
0	0
1	0
2	0
3	0
4	0

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If $\omega = 0$, then the scheme becomes the L -point Deslauriers–Dubuc interpolatory scheme, as we will see later in Example 1. Note that the support of the mask is $\mathbb{Z} \cap [-L, \dots, L]$. As an example, the stencil for the case $L = 4$ is described in Fig. 1(B).

Case 2: L is odd, i.e., $L = 2N + 1$.

On the purpose of obtaining symmetric rules, we employ $L + 1 = 2(N + 1)$ -point scheme reproducing polynomials in $\Pi_{<L}$, and define new (refined) values at $\frac{1}{4}$ and $\frac{3}{4}$ locations between successive old points. Based on this idea, the masks $\{a_{j-2n}: n = -N, \dots, N + 1\}$ with $j = 0, 1$ can be given by solving the linear systems: For the even mask $\{a_{2n}: n \in \mathbb{Z}\}$,

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Then the obtained subdivision rule satisfies the following relation

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The general forms of the masks of S_L . The last two columns indicate the maximum smoothness of S_L and the corresponding ranges of ω , which are obtained by computing $\|(\frac{1}{2}S_L)^{13}\|_{\infty} < 1$ with MAPLE 8, digits = 15

L	Mask	C^r	Range of w
1	$[w, 1 - w, 1 - w, w]$	C^1	$w = \frac{1}{4}$
2	$[w, \frac{1}{2}, 1 - 2w, \frac{1}{2}, w]$	C^2	$w = \frac{1}{8}$
3	$[-w, -\frac{3}{32} + w, \frac{5}{32} + 3w, \frac{15}{16} - 3w, \frac{15}{16} - 3w, \frac{5}{32} + 3w, -\frac{3}{32} + w, -w]$	C^2	$0.030799 < w < 0.085930$
4	$[-w, -\frac{1}{16}, 4w, \frac{9}{16}, 1 - 6w, \frac{9}{16}, 4w, -\frac{1}{16}, -w]$	C^3	$0.020262 < w < 0.044039$
5	$[w, \frac{35}{2048} - w, -\frac{45}{2048} - 5w, -\frac{63}{512} + 5w, \frac{105}{512} + 10w, \frac{945}{1024} - 10w, \frac{945}{1024} - 10w, \frac{105}{512} + 10w, -\frac{63}{512} + 5w, -\frac{45}{2048} - 5w, \frac{35}{2048} - w, w]$	C^3	$0.006261 < w < 0.016737$
6	$[w, \frac{3}{256}, -6w, -\frac{25}{256}, 15w, \frac{150}{256}, 1 - 20w, \frac{150}{256}, 15w, -\frac{25}{256}, -6w, \frac{3}{256}, w]$	C^4	$0.004495 < w < 0.008855$
7	$[-w, -\frac{231}{65536} + w, \frac{273}{65536} + 7w, \frac{1001}{32768} - 7w, -\frac{1287}{32768} - 21w, -\frac{9009}{65536} + 21w, \frac{15015}{65536} + 35w, \frac{15015}{16384} - 35w, \frac{15015}{16384} - 35w, \frac{15015}{65536} + 35w, -\frac{9009}{65536} + 21w, -\frac{1287}{32768} - 21w, \frac{1001}{32768} - 7w, \frac{273}{65536} + 7w, -\frac{231}{65536} + w, -w]$	C^4	$0.001598 < w < 0.003228$
8	$[-w, -\frac{5}{2048}, 8w, \frac{49}{2048}, -28w, -\frac{245}{2048}, 56w, \frac{1225}{2048}, 1 - 70w, \frac{1225}{2048}, 56w, -\frac{245}{2048}, -28w, \frac{49}{2048}, 8w, -\frac{5}{2048}, -w]$	C^5	$0.001132 < w < 0.001754$
9	$[w, \frac{6435}{8388608} - w, -\frac{7293}{8388608} - 9w, -\frac{8415}{1048576} + 9w, \frac{9945}{1048576} + 36w, \frac{85085}{2097152} - 36w, -\frac{109395}{2097152} - 84w, -\frac{153153}{1048576} + 84w, \frac{255255}{1048576} + 126w, \frac{3828825}{4194304} - 126w, \frac{3828825}{4194304} - 126w, \frac{255255}{1048576} + 126w, -\frac{153153}{1048576} + 84w, -\frac{109395}{2097152} - 84w, \frac{85085}{2097152} - 36w, \frac{9945}{1048576} + 36w, -\frac{8415}{1048576} + 9w, -\frac{7293}{8388608} - 9w, \frac{6435}{8388608} - w, w]$	C^5	$0.000394 < w < 0.000629$
10	$[w, \frac{35}{65536}, -10w, -\frac{405}{65536}, 45w, \frac{567}{16384}, -120w, -\frac{2205}{16384}, 210w, \frac{19845}{32768}, -252w + 1, \frac{19845}{32768}, 210w, -\frac{2205}{16384}, -120w, \frac{567}{16384}, 45w, -\frac{405}{65536}, -10w, \frac{35}{65536}, w]$	C^6	$0.000301 < w < 0.000355$